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(54) **AUXILIARY IN-PLANE MAGNET INSIDE A NESTED UNBALANCED MAGNETRON**

(75) Inventor: **Tza-Jing Gung**, Sunnyvale, CA (US)

(73) Assignee: **Applied Materials, Inc.**, Santa Clara, CA (US)

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(52) **U.S. Cl.** ..... **204/298.2; 204/298.19**

(58) **Field of Search** ..... **204/298.19, 298.2**

(56) **References Cited**

**U.S. PATENT DOCUMENTS**

6,183,614 B1 2/2001 Fu ..... 204/298.2

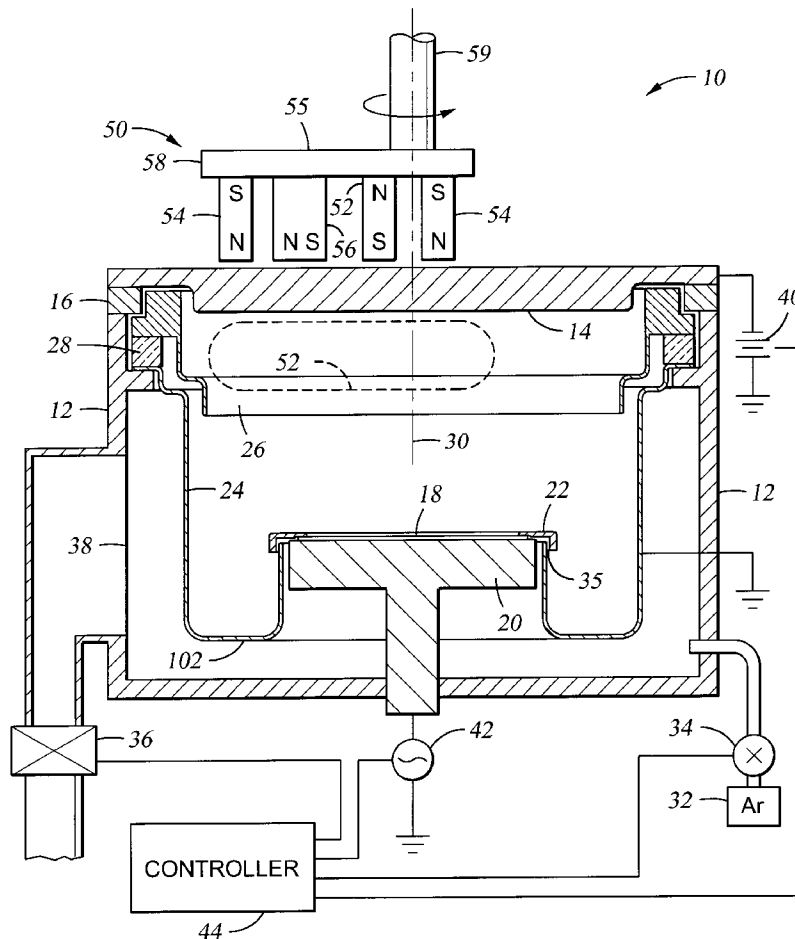
*Primary Examiner*—Rodney G. McDonald

(74) *Attorney, Agent, or Firm*—Charles S. Guenzer, Esq.

(57) **ABSTRACT**

An unbalanced magnetron rotatable about the back of a sputtering target and including a nested magnetron part having an outer magnetic pole of a first magnetic polarity surrounding an inner magnetic pole of an opposed second magnetic polarity and an auxiliary magnet increasing the unbalance and adjusting the uniformity of sputtering. In a first embodiment, the auxiliary magnet is horizontally magnetized and placed between the inner pole and the portion of the outer pole near the target periphery. This embodiment most strongly affects the sputtering erosion pattern near the target periphery. In a second embodiment, the auxiliary magnet is vertically magnetized and placed on an opposite side of the rotation axis from the major portion of the nested magnetron part. This embodiment most strongly affects the vertical magnetic field distribution near the wafer and can produce a more uniform magnetic field at the wafer. The two embodiments can be combined.

**18 Claims, 8 Drawing Sheets**



*Fig. 1*

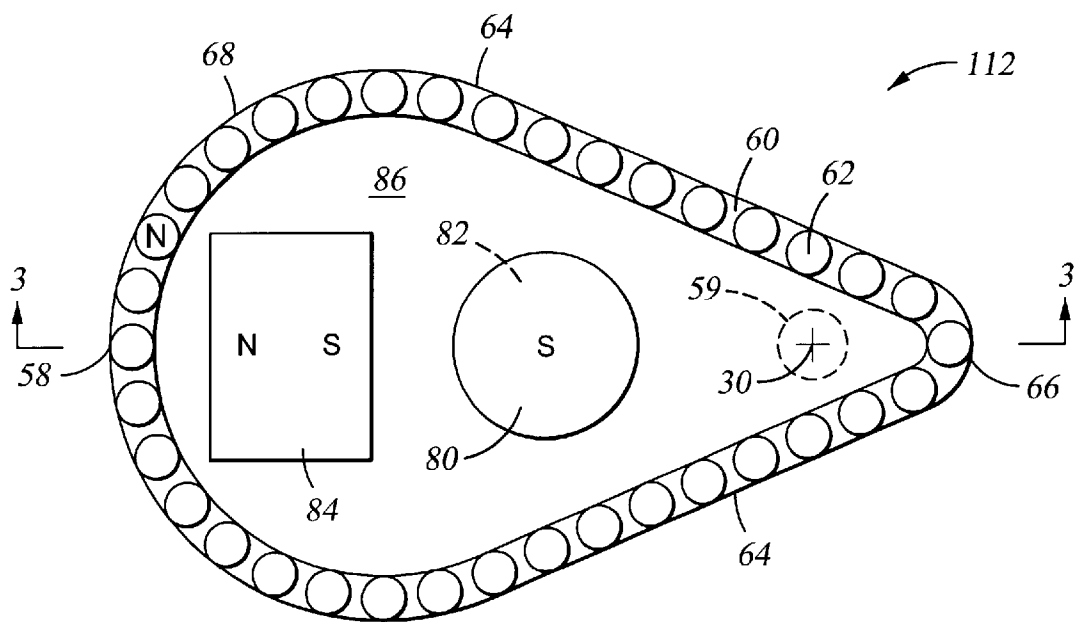


Fig. 2

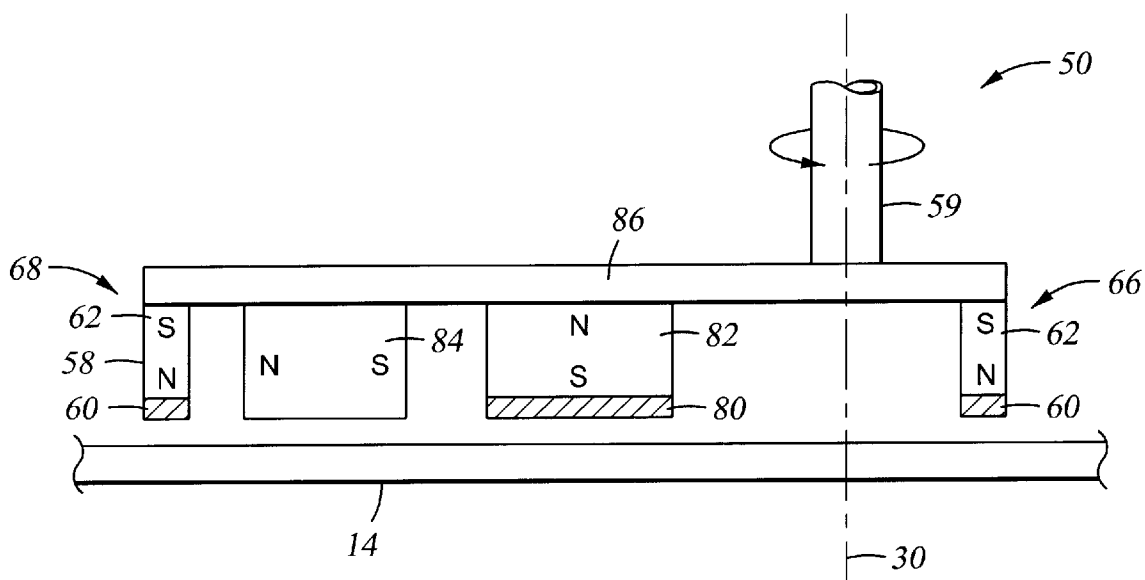


Fig. 3

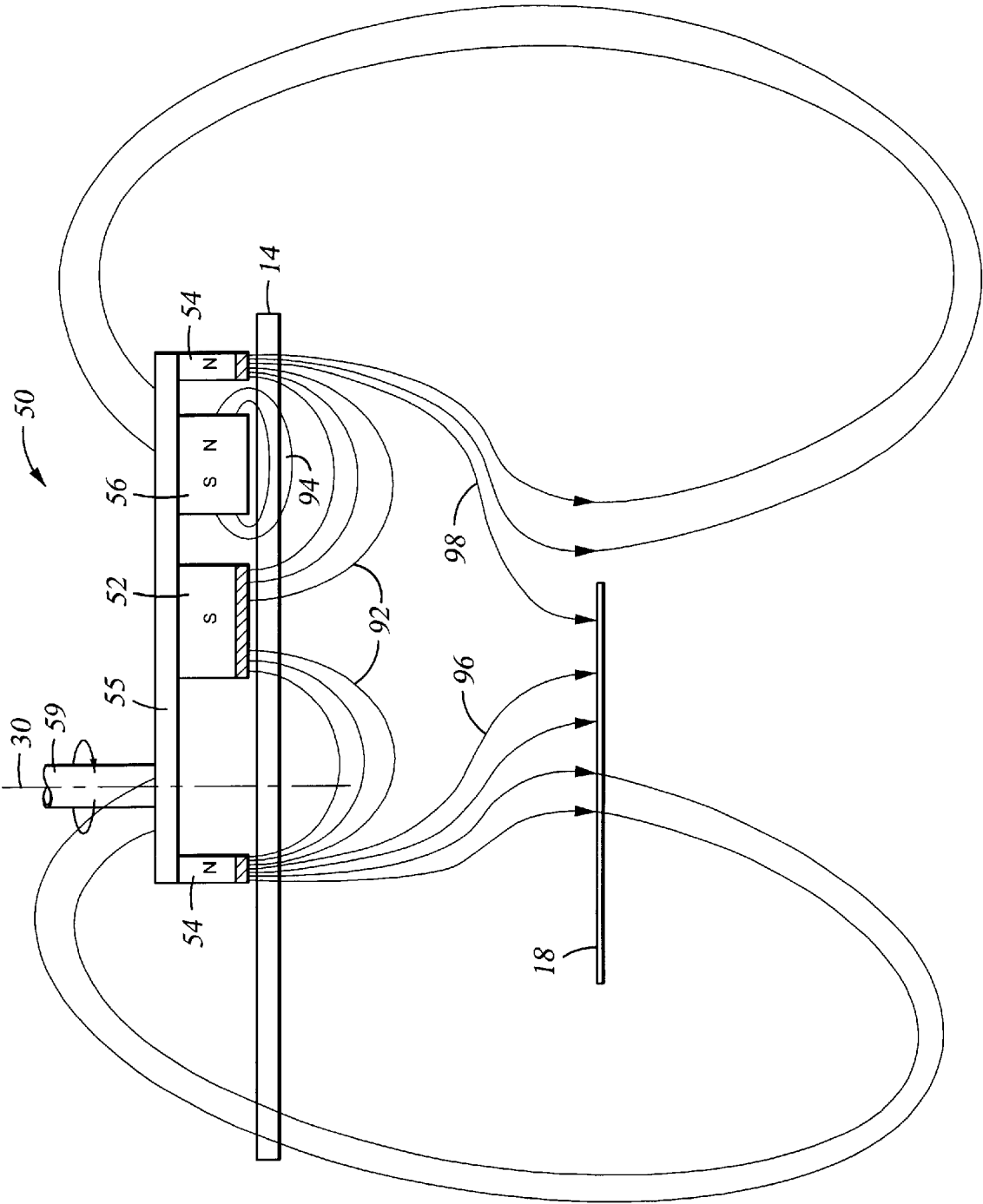


Fig. 4

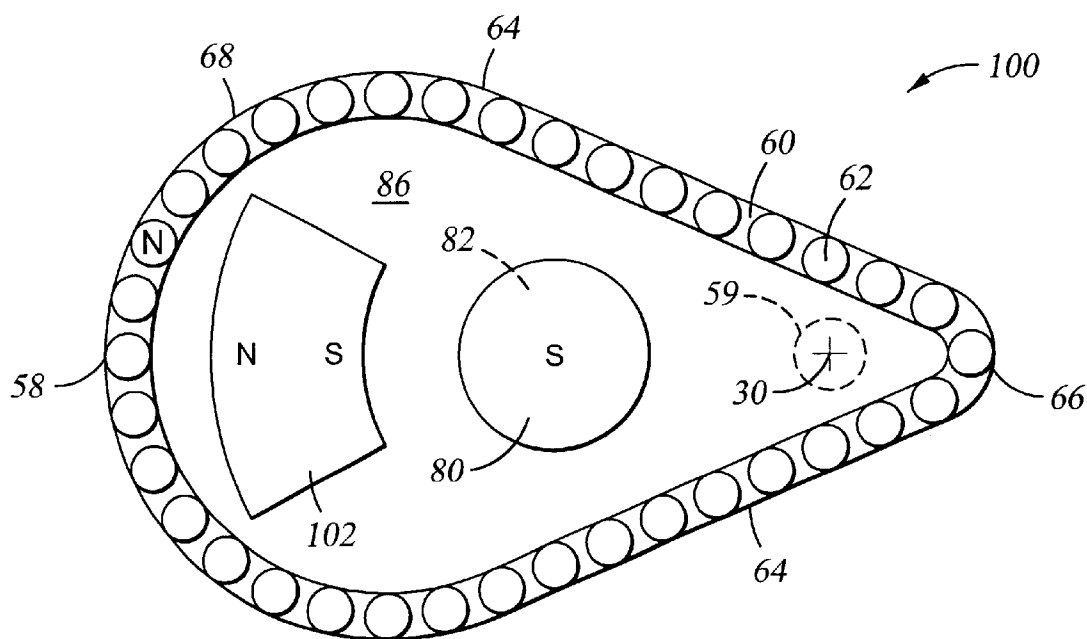


Fig. 5

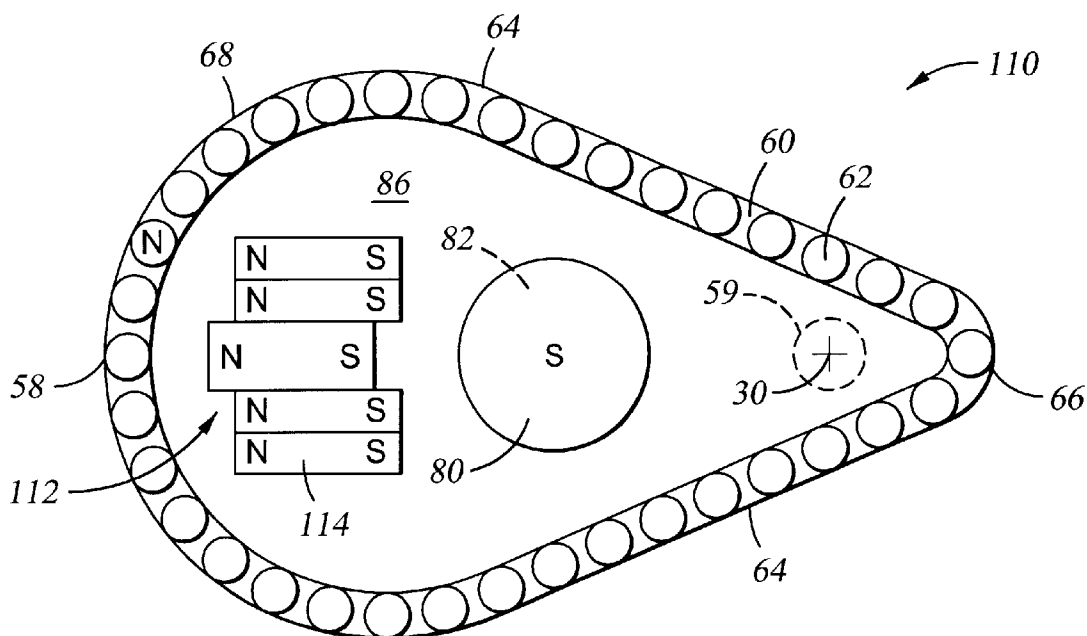


Fig. 6

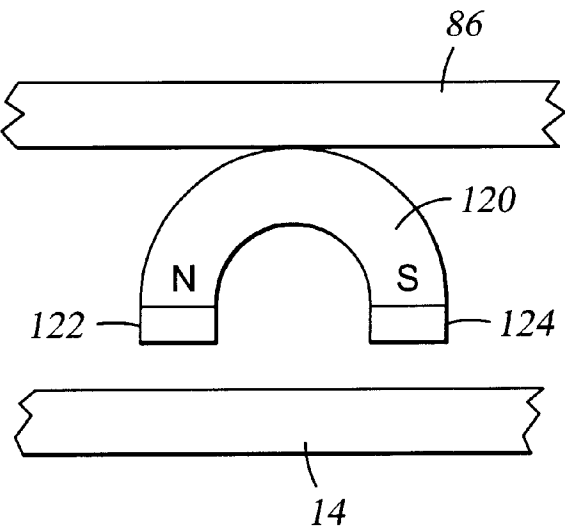


Fig. 7

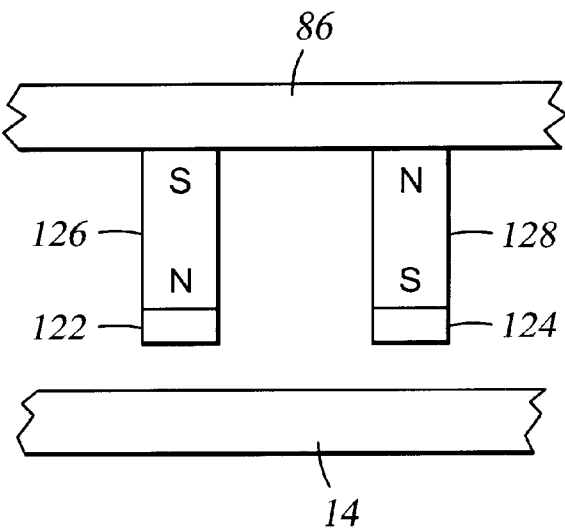


Fig. 8

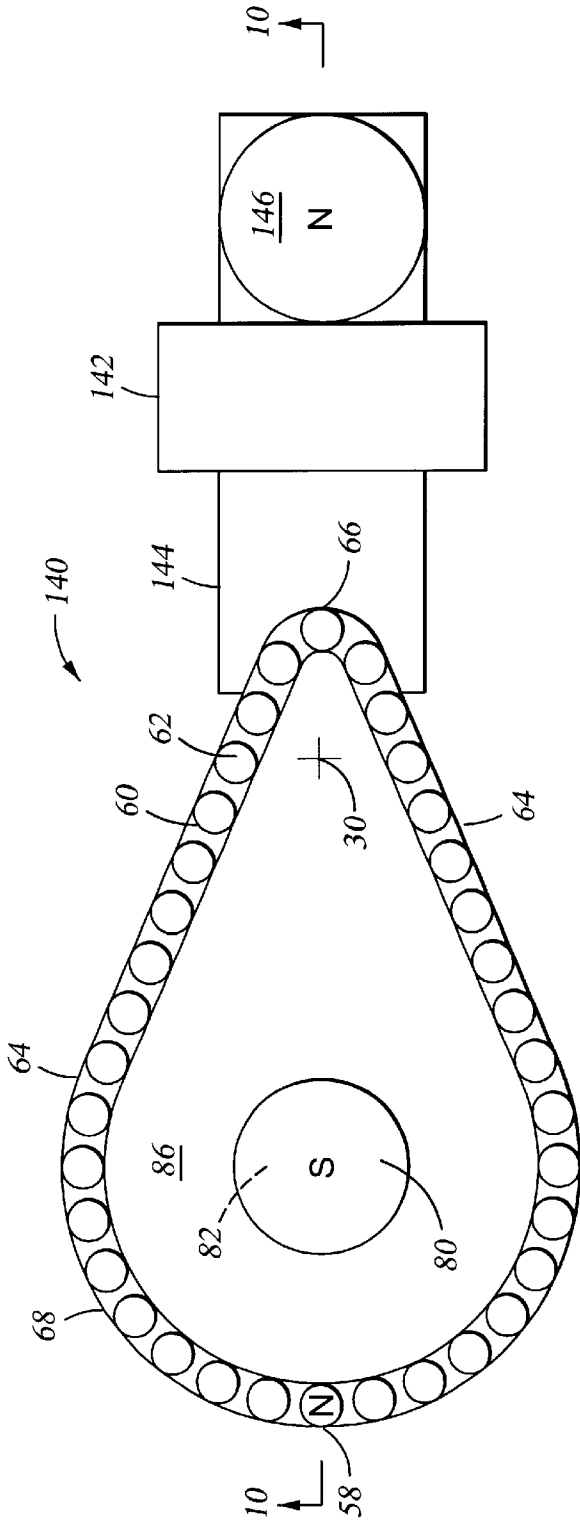


Fig. 9

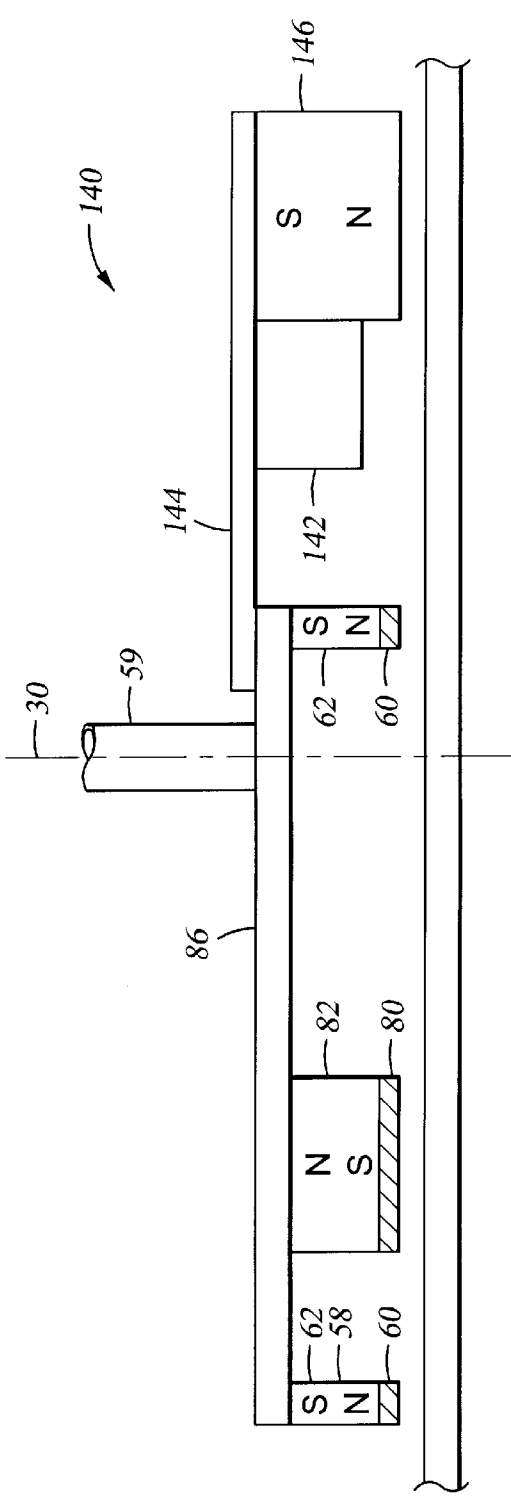


Fig. 10

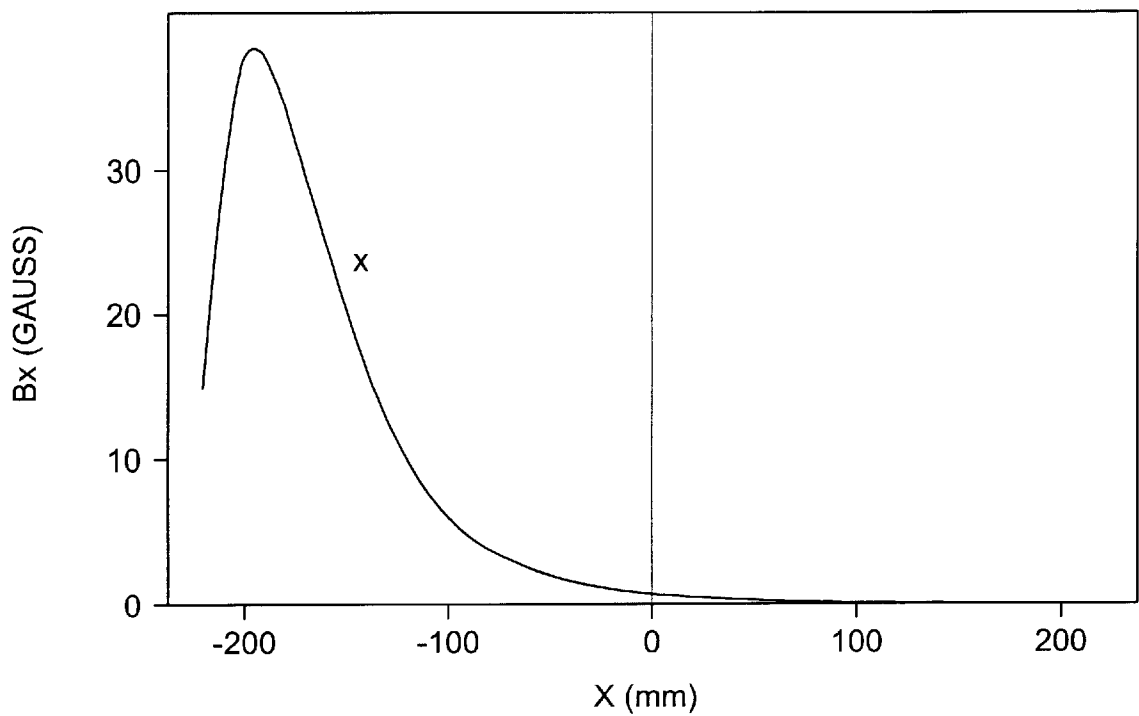


Fig. 11

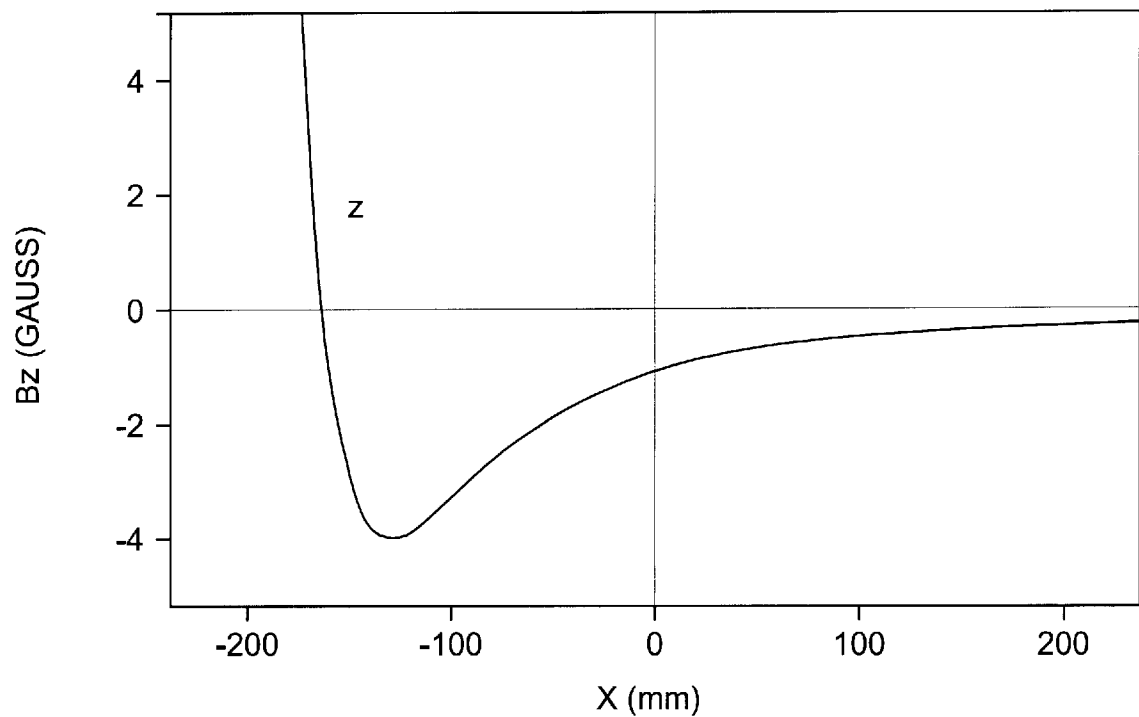


Fig. 12

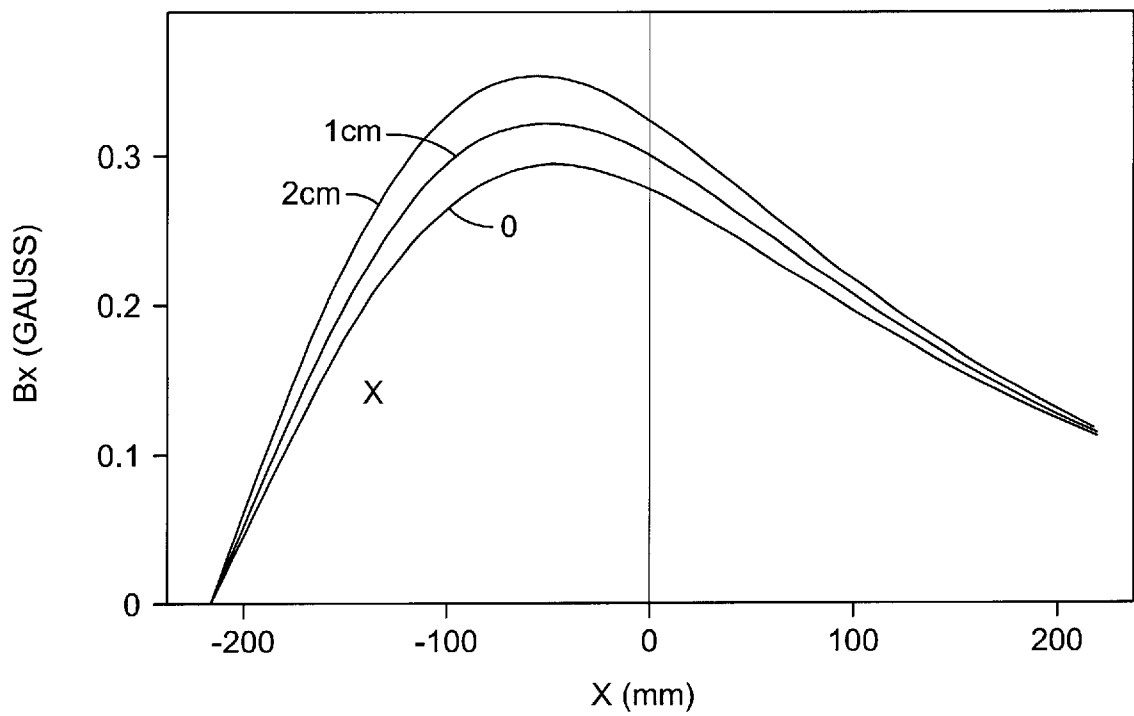


Fig. 13

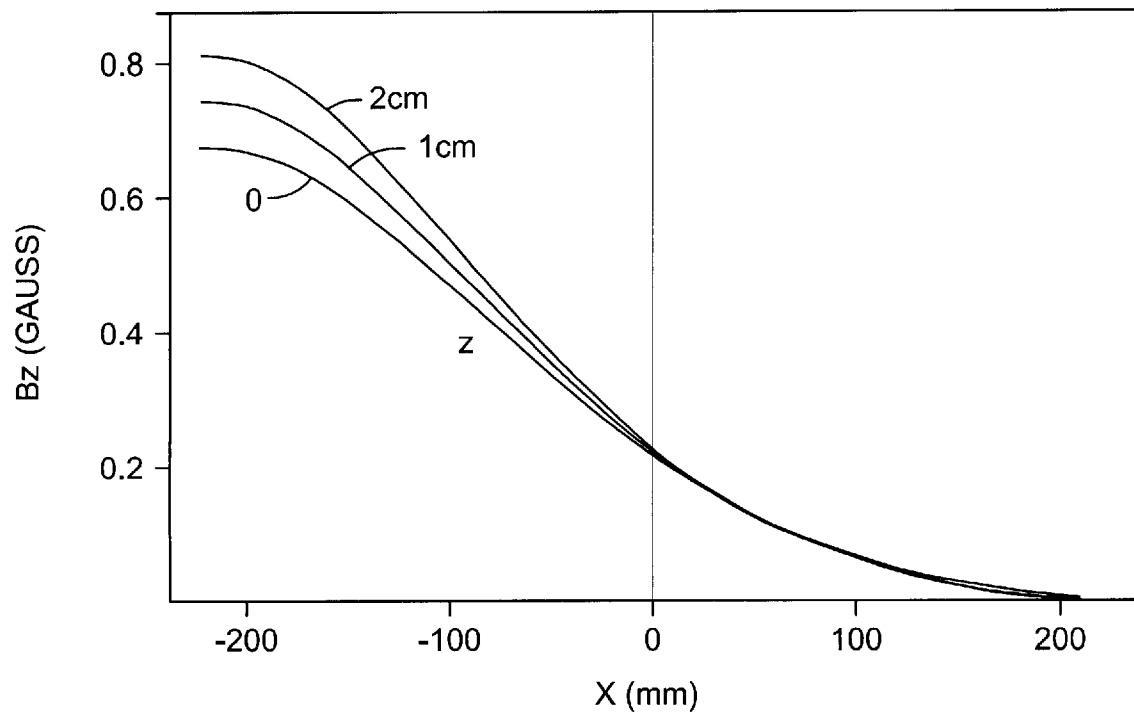


Fig. 14

# AUXILIARY IN-PLANE MAGNET INSIDE A NESTED UNBALANCED MAGNETRON

## RELATED APPLICATION

This invention is related to patent application Ser. No. 09/924,251, concurrently filed on Aug. 7, 2001 allowed.

## BACKGROUND OF THE INVENTION

### 1. Field of the Invention

The invention relates generally to sputtering of materials. In particular, the invention relates to a magnetron creating a magnetic field to enhance sputtering.

### 2. Background Art

Sputtering, alternatively called physical vapor deposition (PVD), is the most prevalent method of depositing layers of metals and related materials in the fabrication of semiconductor integrated circuits. The semiconductor industry typically uses DC magnetron sputtering in which a wafer to be sputter deposited is placed in opposition to a metal target across a plasma reactor chamber filled with an argon working gas. The target is biased sufficiently negatively with respect to the chamber that the argon is excited into a plasma. The positively charged argon ions are strongly accelerated toward the negatively biased target and sputter metal atoms from it. The metal atoms dislodged from the target fall at least in part on the wafer and are deposited in a layer thereon.

In metal sputtering, the target or at least its inner surface has substantially the same metallic composition as that desired for the sputter deposited layer, for example, aluminum, copper, titanium, tantalum, tungsten, etc. In reactive sputtering, a chemically reactive gas such as nitrogen is additionally supplied into the chamber and the reactive gas reacts with sputtered metal atoms at the wafer surface to deposit a metal compound on the wafer, such as the refractory metal nitrides TiN, TaN, WN. The refractory nitrides are particularly useful as barrier layers between a dielectric and a later sputtered metal layer, and a layer of the associated refractory metal is sputtered first onto the dielectric to serve as a glue layer promoting adhesion of the metal to the dielectric. Accordingly, it is often advantageous to use the same sputter reactor to deposit a bilayer liner of, for example, Ti/TiN, Ta/TaN, or W/WN. Sputtering is also used to coat the sides of a via hole with a thin copper seed layer that nucleates and provides an electrode for subsequent filling of copper into the hole by electrochemical plating (ECP).

However, for advanced integrated circuits, sputtering suffers from the problem that sputter deposition, as described above, involves a fundamentally ballistic process of transporting sputtered atoms from the target to the wafer. In the process, the sputtered atoms are emitted in a broad pattern about the normal to the target. Such a distribution is ill suited to filling narrow holes, such as via holes extending through an inter-level dielectric layer separating two layers of metallization. Such via holes in advanced devices may have aspect ratios of 3:1 and greater. A broad sputtering pattern causes the top of the high aspect-ratio hole to close before the bottom is filled. As a result, voids form in the sputtered via metallization. Similarly, the sputtered liner layers tend to be much thicker at the top of the via hole than at the bottom.

One method of adapting sputtering to deep hole filling, as well as to other applications, is self-ionized plasma (SIP) sputtering, as disclosed by Fu in U.S. Pat. No. 6,183,614, by Chiang et al. in U.S. patent application, 09/414,614, filed

Oct. 8, 1999 now U.S. Pat. No. 6,398,929, and by Fu et al. in U.S. patent application, Ser. No. 09/546,798, filed Apr. 11, 2000 and now issued as U.S. Pat. No. 6,306,265, all three incorporated herein by reference in their entireties. SIP sputtering allows a significant fraction of the sputtered atoms to be ionized using a somewhat conventional sputtering reactor. The charged sputtered metal ions can be electrically attracted into narrow via holes in the wafer. Furthermore, the sputtered metal ions can in part be attracted back to the target to further sputter the target, thereby allowing the pressure of the argon working gas to be significantly decreased. In the case of copper, it is possible to eliminate the need for the argon working gas after the plasma has been ignited in a process called sustained self-sputtering (SSS).

Most SIP magnetrons include an outer pole of a first magnetic polarity arranged in a closed band surrounding an inner pole of an opposed, second magnetic polarity. Further, the total magnetic flux integrated over the area of the outer pole, also called the total magnetic intensity, is significantly larger than that of the inner pole, preferably by a factor of at least 1.5. The resultant unbalanced magnetron produces a magnetic field component projecting from the outer pole towards the wafer before that component bends back to close on the back of the outer pole. Such a projecting magnetic field has several advantages. It extends the plasma farther away from the target; it guides ionized sputtered particles towards the wafer; and, it reduces plasma electron leakage to the chamber walls.

An SIP magnetron should be relatively small in order to increase the effective plasma power density, which for a fixed target power increases inversely with the area of the magnetron. A prevalent design for a SIP magnetron includes an outer pole having a generally triangular shape with the triangular base of the outer pole positioned near the periphery and the triangular apex located near the central axis of the chamber about which the magnetron is rotated to provide angularly uniform sputtering of the target.

Such a simply shaped magnetron is relatively constrained in the ease of optimizing its design for the various requirements of a magnetron intended for commercial usage, such as sputtering uniformity, high sputtering rate, projection of the magnetic field, and low operating pressure. A further problem is that sputtered material tends to redeposit at the periphery of the target where the magnetic field tends to be less. The redeposited material is not effectively resputtered and has a crystallography different than the original target. As a result, the redeposited material grows in thickness and tends to flake off, thereby producing deleterious particles which significantly reduce chip yield.

One technique for increasing the peripheral magnetic field and hence preventing redeposition from accumulating includes moving the inner pole closer to the outer pole near the target periphery. However, this change pushes the high-density plasma closer to the grounded or floating shield near the target edge. The proximity of the plasma to such an electrically biased shield has been observed to cause problems with the stability of the plasma as the magnetron sweeps the plasma around the target periphery. Arcing to the shields may occur, which also produces particles. The plasma may shrink away from the shields or even collapse in some situations, obviously severely impacting deposition uniformity and yield. SIP sputtering typically relies upon high target powers, usually identified by high target voltage, for example, around -500 to -800 VDC and requiring powers of 30 kW or more. For reasons of economy, the size of the power supply is selected to operate near its limit. With

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the plasma positioned close to the shields, plasma fluctuations have been observed which temporarily raise the target voltage to -1000 VDC, sufficient to bum out the typically used power supplies.

Accordingly, it is desired to provide an unbalanced magnetron having additional design freedom. It is also desired to increase the sputtering rate near the target periphery without bringing the principal magnetic field too close to the periphery. It is further desired to improve the uniformity of sputter deposition.

A further problem arises from the desire to reduce the argon pressure so that the plasma is barely supported and is operating in conditions close to extinguishment. Such a plasma is unstable. Even if it does not extinguish, it may change in intensity and distribution, effects which degrade the desired uniformity of sputter deposition.

## SUMMARY OF THE INVENTION

An unbalanced magnetron useful for DC sputtering having a nested magnetron and an auxiliary magnet. The magnetron is rotated about a center of the target being sputtered.

In one aspect of the invention, the auxiliary magnet is a horizontally magnetized planar magnet placed between the inner and outer poles on the side of the inner pole closer to the target periphery. The poles of the planar magnet may be chosen to reinforce the pole of the inner and outer magnetic poles closer to the target. Such a planar auxiliary magnet increases the sputtering rate near the outer target periphery.

In another aspect of the invention, the auxiliary magnet is a vertically magnetized magnet placed on an opposite side of the rotation axis from the major portion of the nested magnetron. Preferably, the polarity of the auxiliary magnet corresponds to the polarity of the outer magnetic pole. Such a vertical auxiliary magnet increases the vertical magnetic field adjacent the wafer.

The two aspects may be combined in a single magnetron.

The nested magnetron has an inner pole of one magnetic polarity surrounded by an outer pole of another polarity and including an auxiliary magnet and is preferably an unbalanced magnetron in which the total magnetic flux of the outer pole is significantly greater than that of the inner pole, for example, in a ratio of at least 1.5. The nested magnetron may have a generally triangular outer shape with the axis of rotation near the apex of the triangle and the base of the triangle near the target periphery.

The auxiliary magnet may be used to optimize various portions of the magnetic field distribution. One effect of the auxiliary magnet may be to increase the unbalance of the magnetic field distribution.

## BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 is a cross-sectional view of a self-ionized plasma (SIP) sputter reactor.

FIG. 2 is a bottom plan view of a magnetron of the invention usable with the SIP sputter reactor of FIG. 1.

FIG. 3 is a cross-sectional view of the magnetron of FIG. 2 taken along view line 3—3.

FIG. 4 is a cross-sectional view of the magnetic field distribution produced by the magnetron of FIGS. 2 and 3.

FIG. 5 is a bottom plan view of a first variant of the magnetron of FIGS. 2 and 3.

FIG. 6 is a bottom plan view of a second variant of the magnetron of FIGS. 2 and 3.

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FIG. 7 is a cross-sectional view of a first alternative to the horizontally magnetized planar magnet using one of more horse shoe magnets.

FIG. 8 is a cross-sectional view of a second alternative using pairs of magnets with vertically opposed magnetization.

FIG. 9 is a bottom plan view of another magnetron of the invention using an externally vertically magnetized magnet.

FIG. 10 is a cross-sectional view of the magnetron of FIG. 9 taken along view line 10—10.

FIGS. 11 and 12 are graphs of the magnetic field near the target produced by the external vertically magnetized auxiliary magnet.

FIGS. 13 and 14 are graphs of the magnetic field near the wafer produced by the externally vertically magnetized auxiliary magnet.

## DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENTS

On embodiment of the invention, illustrated in the cross-sectional view of FIG. 1 includes a self-ionized plasma (SIP) sputter reactor 10 and an inventively configured magnetron 50, which is illustrated in more detail in the schematic bottom plan view of FIG. 2 and the side cross-sectional view of FIG. 3.

Concentrating first on the chamber parts of FIG. 1, the reactor 10 includes a chamber wall 12 supporting a biased metal target 14 through a dielectric isolator 16, thereby forming a sealed vacuum chamber. A wafer 18 is held on a pedestal electrode 20 by, for example, a clamping ring 22 although an electrostatic chuck may alternatively be used. The chamber walls 12 are protected from sputter deposition by an electrically grounded shield 24, which also acts as an anode to the target cathode. An electrically floating shield 26 supported on a second dielectric isolator 28 is arranged about a central chamber axis 30 between the grounded shield 24 and the target 14. A negative charge from plasma electrons inherently accumulates on the floating shield 26 during sputtering and repels deposition of further plasma electrons, thereby reducing electron leakage and extending the plasma closer to the wafer 18.

Argon working gas is supplied into the chamber 12 from a gas supply 32 and is metered by a mass flow controller 34. The working gas flows into the processing region through a gap 35 between the pedestal 20, the grounded shield 24, and the wafer clamp 22. A vacuum pumping system 36 connected to a pumping port 38 maintains the interior of the chamber 12 at a low but controllable pressure. A negative DC power supply 40 biases the target 14 to about -500 to -600 VDC, which after plasma ignition is sufficient to maintain the argon working gas as a plasma. Ignition is usually accomplished at a higher voltage and higher chamber pressure. The negative bias attracts to the target 14 positively charged ions, whether of argon or of the metal in SIP sputtering, where they sputter target atoms, which are thereafter deposited on the wafer 18 to form a layer of sputtered material. An RF power supply 42 applies RF power to the pedestal electrode 20, which causes it to develop a negative DC self-bias in the presence of a plasma. A computerized controller 44 controls the power supplies 40, 42, the mass flow controller 34, and the pumping system 36, thereby controlling the sputtering conditions.

The magnetron 50 is located in back of the target 14 to generate a magnetic field adjacent to the front (bottom) of the target 14. The magnetic field traps electrons, which

raises the plasma density in a high-density plasma region **52**, thereby increasing the sputtering rate. An argon chamber pressure of about 6 to 10 milliTorrs is typically required to ignite the plasma. However, if the density of metal ions in the high-density plasma region **52** is sufficiently high, the supply of argon can be reduced and sometimes eliminated so that a significant portion if not all of the target sputtering is effected by metal ions in the SIP process. Under the proper conditions, chamber pressure for SIP sputtering can be reduced to well below 1 milliTorrs. The very low sputtering pressures are advantageous in reducing scattering of the sputtered atoms as they move towards the wafer and in reducing the temperature of the wafer since energetic argon ions are no longer bombarding it.

SIP sputtering is promoted by high target power and a small-area intense magnetic field produced by the magnetron **50**, as well as designing the magnetron to minimize plasma leakage to the shields and target. Such a magnetron **50** includes an inner magnet pole **52** of one vertical magnetic polarity surrounded by an outer magnet pole **54** of the opposed vertical magnetic polarity in a nested configuration. One or both of the inner and outer magnet poles magnet poles **52**, **54** may be composed of multiple magnets with perhaps a pole face linking the magnets within the pole. The magnetic polarities of the magnet poles **52**, **54** illustrated in FIG. 2 are the polarities at one end of the magnets with the other ends having the opposite polarity. The inner and outer magnet poles **52**, **54** are magnetically coupled by a magnetic yoke **55** on their ends away from the target **30**.

Additionally, according to one aspect of the invention, the magnetron **50** includes a horizontally magnetized planar magnet **56** arranged between the inner and outer magnet poles **52**, **54** on the side of the inner pole **52** away from the central axis and towards the outer periphery **58** of the rotating magnetron **50**. Preferably, the radially (with respect to the rotation axis **30**) outer horizontal magnetic polarity of the planar magnet **56** matches the vertically downward magnetic polarity of the outer magnet pole **54**, and its radially inner horizontal magnetic polarity matches the vertically downward magnetic polarity of the inner magnet pole **52**.

The inner and outer magnetic poles **52**, **54** are magnetically sized to produce an unbalanced magnetron in which the total magnetic flux or intensity, that is, flux density integrated over the surface of the pole face produced by the outer pole **54** is significantly larger than the total magnetic flux produced by the inner pole **52**, for example, by a factor of at least 1.5. The integrated magnetic flux may be referred to as the total magnetic intensity. Because the planar magnet **56** has poles assisting the inner magnetic pole **52** and the more closely adjacent portion of the outer pole **54**, the planar magnet **56** contributes to a yet more strongly unbalanced magnetron though with different characteristics in part than a nested unbalanced magnetron with only a single pair of nested poles.

The magnetron **50** has a relatively small area and is substantially disposed on one side of the central chamber axis **30**. An unillustrated motor drives a motor shaft **59** extending along the central axis **30** and supporting the magnetron **50** through the magnetic yoke **55**. Thereby, the magnetron is swept around the target **14** to produce a circularly symmetric erosion pattern.

The magnetron **50** is illustrated in more detail in the bottom plan view of FIG. 2 and the cross-sectional view of FIG. 3 taken along view line 3—3 of FIG. 2. The outer pole of a first magnetic polarity is defined by an outer pole face

**60** arranged in a closed band underlying a plurality of cylindrical magnets **62** of one vertical magnetic polarity, for example, N, extending along the central axis **30**. Both the pole face **60** and the cylindrical magnets **62** are arranged in a smoothly truncated triangular shape having two straight side portions **64** of preferably equal length inclined to each other and joined at their apex ends by a small arced portion **66** and at their base ends by a large arced portion **68**, defining at its center the outer periphery **58** of the rotating magnetron **50**. The large arced portion **68** extends over slightly more than 180° and is circularly symmetric about an arc center falling on the axis of symmetry of the magnetron shaped generally like an isosceles triangle. The small arced portion **66** is also circularly symmetric, but with a smaller radius. The apex angle of the triangular shape, as illustrated, is 48°. Other values of the apex angle may be chosen, for example, in the range of 35° to 60°. The width of the band of the outer pole face **60** is approximately equal to the diameters of the cylindrical magnets **62** and includes a large aperture within the closed band.

The inner pole of an opposed second magnetic polarity is defined by a circular inner pole face **80** and a large, inner cylindrical magnet **82** of a vertical magnetic polarity opposite that of the smaller, outer cylindrical magnets **62**, for example S. The center of the inner cylindrical magnet **82** is displaced away from the arc center of the large arc portion **68** of the outer pole face **68** in a direction towards its inner apex **66**. Other magnet arrangements may be used for both the inner and outer poles.

The inner and outer magnets **82**, **62** are supported on and magnetically coupled by a magnetic yoke **86** supported on the rotation shaft **59**. The magnetic yoke and the pole faces **60**, **80** are formed, for example, of a soft, magnetic material, such as SS410 stainless steel.

A rectangularly shaped planar bar magnet **84** is placed between the inner cylindrical magnet **82** and the outer cylindrical magnets **62** near the magnetron's outer periphery **58**. It is horizontally magnetized with the magnetic pole, N as illustrated, near the magnetron outer periphery **58** matching that of the target-side pole of the outer cylindrical magnets **62**, and the other pole matching the target-side pole of the adjacent inner magnet **80**. The planar magnet **84** and its magnetization direction extend generally along the radial axis of symmetry of the magnetron **50**. The planar magnet **84** includes no bottom magnetic pole face, which would tend to magnetically short it. As a result, the bottom face of the planar magnet **84** is preferably aligned with the bottom faces of the poles pieces **60**, **80** relatively close to the back of the target **14**. On the other hand, it has been observed that the planar magnet **84** may be directly attached to the magnetic yoke **86** without degrading its performance. Nonetheless, it is preferred that a non-magnetic spacer of thickness of about 2 mm be used between the planar magnet **84** and the magnetic yoke **86**.

All the magnets **62**, **82**, **84** are preferably permanent magnets. The magnet configuration may be more complex than that described above, for example, including multiple inner magnets **82** and having outer magnets **62** of different intensities.

The magnetic field distribution for such a magnetron configuration is illustrated in the cross-sectional view of FIG. 4. It includes a generally semi-toroidal field **92** typical of many SIP magnetrons. It additionally includes a horizontal component **94** extending generally parallel beneath the planar magnet **56** and generally reinforcing the semi-toroidal field **92** in the outer region of the target **14**, thereby increas-

ing the plasma density and hence sputtering rate in that region. Small magnetrons typically used in the past for SIP sputtering generally suffer from low sputtering rates in the outer region of the target. The planar magnet **56** relieves this problem by increasing the horizontal magnetic field adjacent the outer region of the target. The magnetic field also includes downwardly projecting portions **96**, **98** extending downwardly along the chamber walls and inwardly towards the wafer. These downwardly projecting portions **96**, **98** extend the plasma, prevent plasma leakage to the chamber walls, and guide ionized sputter atoms towards the wafer **18**. The projecting portions **96**, **98** close generally near the side or rear of the magnetron **50**.

These calculations support the belief that the erosion characteristics and plasma density are controlled by the near-field components of the magnetic field distribution near the target **14** while uniformity is controlled by the far-field components away from the target **14** and towards the wafer **18**. Although the auxiliary planar magnet **56** increases the unbalance of the magnetron, thereby causing the magnetic field to more strongly project to the wafer **18**, the principal effect of the planar magnet **56** is to intensify the horizontal magnetic field close to the target **14**, thus increasing the plasma density and the sputtering rate in the outer peripheral areas of the target **14**.

In a comparative example, an unbalanced magnetron without an auxiliary planar magnet was used in an SIP reactor to sputter TiN or TaN. This combination produces reasonably good uniformity of 4%, but a 3 mm redeposition zone develops at the edge of the wafer. In contrast, when the planar horizontally magnetized auxiliary magnet of FIGS. 1-3 is used in an inventive example, edge redeposition is eliminated with no degradation in the uniformity.

A related embodiment of the invention, which improves the effect of the planar magnet, includes a magnetron **100** including an arc-shaped planar magnet **102**, as illustrated in the bottom plan view of FIG. 5, instead of the rectangular planar magnet **84**. The curvatures of inward arced face should be based on the curvature of the inner pole face **80** so as to produce a nearly uniform gap. The arc-shaped planar magnet **100** is horizontally magnetized either parallel to the symmetry axis of the illustrated magnetron **100** or, with more difficulty, with a varying magnetization direction having an angle varying to be more closely perpendicular to the tangent of the arc of the planar magnet **102**.

Yet another related embodiment of a magnetron **110**, illustrated in the bottom plan view of FIG. 6, allows further optimization with reduced fabrication difficulty and expense by using an arc-shaped array **112** of rectangular plate magnets **114**. In one sub-embodiment, the plate magnets **114** have equal lengths to closely resemble the arc-shaped planar magnet **100** of FIG. 5. The arc-shaped array **112** may be made to differ primarily from the arc-shaped planar magnet **100** by the presence of jagged edges. In a second sub-embodiment, the plate magnets **114** have varying lengths, preferably with the longer ones towards the central axis of the arc-shaped array **112**. The variation of the lengths allows fine tuning of the magnetic field distribution and further optimization of the sputtering uniformity.

Similar results may be obtained when the horizontally magnetized planar magnet is replaced, as illustrated in the cross-sectional view of FIG. 7, by one or more horse shoe magnets **120** fixed to the magnetic yoke **86** and which may have pole faces **122**, **124** magnetically linking multiple horse shoe magnets **120**. Alternatively, as illustrated in the cross-sectional view of FIG. 8, the planar magnet may be

replaced by oppositely polarized magnet assemblies **126**, **128** fixed to the magnetic yoke **86** and having their respective two pole faces **122**, **124**. The magnet assemblies **126**, **128** may be vertically extending magnet plates or magnet arc segments and may be composed of multiple rod or plate magnets of the indicated magnetic polarity. However, these vertically magnetized configurations produce a magnetic field which projects somewhat further to the bottom of the target than does a horizontally magnetized planar magnet. One of the major advantages of a horizontally magnetized planar magnet is the strong horizontal magnetic field produced close to the bottom face of the target **14**.

A second aspect of the invention includes a magnetron **140** illustrated in the bottom plan view of FIG. 9 and in cross-sectional view of FIG. 10 taken along view line 10-10 of FIG. 9. This magnetron includes the previously described nested magnetron part having an outer pole of a first vertical magnetic polarity made up of an outer pole face **60** and outer magnets **62** and an inner pole of the other vertical magnetic polarity made up of an inner pole face **80** and inner magnet **82**. The center of the cylindrical inner pole is close to the arc center of the large arced portion **68**. The nested magnetron part is mechanically counterbalanced about the rotation axis **30** by a counterbalance weight **142** hung on a counterbalance arm **144** fixed to the magnetic yoke **86**. In this embodiment, an auxiliary vertically magnetized magnet **146** of the first vertical magnetic polarity (that is, the same polarity as the outer pole) is supported on the counterbalance arm **144**, preferably near its distal end on an opposite side of the rotation axis **30** from the nested magnetron part, in particular, the inner pole of the nested magnetron part. Preferably, the counterbalance arm **144** is non-magnetic so that it does not magnetically couple the auxiliary magnet **146** to the other magnets **62**, **82**, but a magnetic counterbalance arm may be used taking into account how it affects the magnetic field.

Referring back to FIG. 4, the effect of the unillustrated vertically magnetized auxiliary magnet **146** is to supplement and intensify the vertically projecting magnetic field lines **96** incident on the wafer **18** and to further spread them to the illustrated left side of the wafer **18**. This effect is supported by calculations of the magnetic field produced by the vertically magnetic auxiliary magnet. The x-component  $B_x$  of the magnetic field is plotted in FIG. 11, and the y-component,  $B_y$ , in FIG. 12, both at vertical positions just below the target. The left sides of the plots correspond to the area of the auxiliary magnet **146**, the right sides to the nested magnetron part. These fields have been designed for a 300 mm-diameter wafer with the center axis at  $x=0$ . It is seen that the vertically magnetized auxiliary magnet has little influence on the illustrated right side corresponding to the area of the nested magnetron part. Therefore, the external vertically magnetized auxiliary magnet has very little effect on the sputtering process as it affects the target, which for reasonably sized magnets is dominated by the nested magnetron part.

However, the auxiliary magnet produces a significant effect near the wafer, and its contribution to the magnetic field at the wafer may be comparable to that produced by the nested magnetron part, which is typically in range of 1 to 2 gauss. A quantification of this relationship is that the maximum vertical magnetic field produced by the nested magnetron at the wafer has a value within a factor of two of the value of the maximum vertical magnetic field produced by the vertically magnetized auxiliary magnet.

The x-component  $B_x$  of the magnetic field produced by the vertically magnetized auxiliary magnet is plotted in FIG.

13 and the y-component  $B_y$  is plotted in FIG. 14 at three vertical distances above the wafer of 0, 1 cm, and 2 cm. It is seen that the contribution from the vertically magnetized auxiliary magnet is strongly vertical near the wafer surface and that the vertical component is strongest on the side of the wafer opposite the nested magnetron. The polarity of the vertical auxiliary magnetic field matches that from the nested magnetron in this region, while the intensity of the vertical contribution from the nested magnetron favors the side of the wafer opposite that favored by the auxiliary magnet. Accordingly, it is possible to obtain an approximately constant vertical magnetic field across the wafer by balancing the magnetic intensities of the nested magnetron and the auxiliary vertical magnet. Furthermore, tailoring the magnetic field near the wafer by adjusting the intensity and location of the auxiliary magnet can be done with very little effect on the magnetic field affecting the target sputtering.

It is thus seen that the horizontally magnetized auxiliary magnet of FIGS. 2 and 3 operates distinctly differently than does the vertically magnetized auxiliary magnet of FIGS. 9 and 10. The former is most directly used to make a more uniform sputtering erosion path in the target; the latter is most directly used to produce a more uniform vertical magnetic field adjacent the wafer, thus promoting sputtering deposition uniformity. Both may be used to improve uniformity of deposition. It is also noted that both types of auxiliary magnets may be included in a single magnetron, one auxiliary magnet being horizontally magnetized and included between the poles of the nested magnetron, the other auxiliary magnet being vertically magnetized and located on the other side of the rotation axis from the nested magnetron.

Such auxiliary magnets thus provide more design variables that can be optimized to obtain a more uniform sputter deposition.

What is claimed is:

1. A sputtering magnetron, comprising:

a nested unbalanced magnetron positionable at a back of a sputtering target, rotatable about a center axis of said target, and comprising an outer magnetic pole of one vertical magnetic polarity surrounding an inner magnetic pole of an opposite magnetic polarity, a total magnetic flux of said outer magnetic pole being at least 150% of a total magnetic flux of said inner magnetic pole; and

an auxiliary permanent magnet rotatable with said nested unbalanced magnetron.

2. The magnetron of claim 1, wherein said auxiliary magnet increases an unbalance of the magnetic field distribution.

3. The magnetron of claim 1, wherein said auxiliary magnet is a magnet magnetized perpendicular to said center axis and positioned between said inner magnetic pole and said outer magnetic pole on a side of said inner magnetic pole opposite said center.

4. The magnetron of claim 3, wherein said auxiliary magnet has magnetic pole facing said inner magnetic pole of the same polarity as a face of said inner magnetic pole facing said target.

5. The magnetron of claim 3, further comprising a second auxiliary magnet magnetized perpendicular to said center axis and positioned on an opposite side of said center from said inner magnetic pole.

6. The magnetron of claim 3, wherein said auxiliary magnet comprises an arc-shaped magnet.

7. The magnetron of claim 3, wherein said auxiliary magnet comprises a plurality of rectangular magnets arranged in an arc-shaped array.

8. A sputtering magnetron, comprising:

a nested unbalanced magnetron positionable at a back of a sputtering target, rotatable about a center axis of said

target, and comprising an outer magnetic pole of one vertical magnetic polarity surrounding an inner magnetic pole of an opposite magnetic polarity, a total magnetic flux of said outer magnetic pole being at least 150% of a total magnetic flux of said inner magnetic pole; and

an auxiliary permanent magnet magnetized perpendicular to said center axis, rotatable with said nested unbalanced magnetron, and positioned between said inner magnetic pole and said outer magnetic pole on a side of said inner magnetic pole opposite said center axis.

9. The magnetron of claim 8, wherein said auxiliary magnet has a magnetic pole facing said inner magnetic pole of the same polarity as a face of said inner magnetic pole facing said target.

10. The magnetron of claim 8, wherein said auxiliary magnet is arc-shaped.

11. The magnetron of claim 8, wherein said auxiliary magnet includes a plurality of plate magnets arranged in an arc-shaped assembly.

12. A sputtering magnetron, comprising:

a nested unbalanced magnetron positionable at a back of a sputtering target, rotatable about a center axis of said target, and comprising an outer magnetic pole of first magnetic polarity along said center axis and surrounding an inner magnetic pole of an opposed, second magnetic polarity, a total magnetic flux of said outer magnetic pole being at least 150% of a total magnetic flux of said inner magnetic pole; and

an auxiliary permanent magnet assembly rotatable with said nested unbalanced magnetron and positioned between said inner magnetic pole and said outer magnetic pole on a side of said inner magnetic pole opposite said center axis and including a first magnet pole of said first magnetic polarity positioned closer to said inner magnetic pole and a second magnet pole of said second magnetic polarity positioned closer to said outer magnetic pole on said side of said inner magnetic pole opposite said center axis.

13. The magnetron of claim 12, wherein said auxiliary magnet assembly includes at least one horse shoe magnet.

14. The magnetron of claim 12, wherein said auxiliary magnet assembly includes at least two magnets of opposite polarities magnetically coupled by a magnetic yoke.

15. A sputtering magnetron, comprising:

a nested unbalanced magnetron positionable at a back of a sputtering target, rotatable about a center axis of said target, and comprising an outer magnetic pole of one vertical magnetic polarity surrounding an inner magnetic pole of an opposite magnetic polarity, a total magnetic flux of said outer magnetic pole being at least 150% of a total magnetic flux of said inner magnetic pole; and

an auxiliary permanent magnet magnetized along a direction perpendicular to said center axis, rotatable with said nested unbalanced magnetron, and positioned between said inner magnetic pole and said outer magnetic pole on a side of said inner magnetic pole opposite said center axis.

16. The magnetron of claim 15, wherein said auxiliary magnet has a magnetic pole facing said inner magnetic pole of the same polarity as a face of said inner magnetic pole facing said target.

17. The magnetron of claim 15, wherein said auxiliary magnet is arc-shaped.

18. The magnetron of claim 15, wherein said auxiliary magnet includes a plurality of plate magnets arranged in an arc-shaped assembly.